

# OXFORD IN YOUR CITY - SANTA BARBARA

## MARCH 25 2020

FOUR SEASONS RESORT, SANTA BARBARA

9.00 - 9.30am	WELCOME & REGISTRATION	
9.30 - 9.45am	<b>Introduction</b>	Emiel Thijssen
9.45 - 10.30am	<b>VCSEL DEVICE MANUFACTURING</b> Low footing process for maximum device performance	Stephanie Baclet
10.30 - 10.45am	COFFEE BREAK	
10.45 - 11.30am	<b>ION BEAM ETCHING AND DEPOSITION</b> for Laser Facet Processing	Pauline Alvarez
11.30 - 12.00am	<b>ATOMIC LAYER ETCHING</b> A new technique for ultra precise and low damage etching	Dr Mark Dineen
12.00 - 1.30pm	NETWORKING LUNCH	
1.30 - 2.15pm	<b>ALD FOR GaN POWER DEVICES</b> Fast plasma enhanced ALD enabling improved interfaces, high quality films & high throughput	Dr Aileen O'Mahony
2.15 - 2.45pm	<b>ION BEAM DEPOSITION</b> for Infrared Sensors	Pauline Alvarez
2.45 - 3.15pm	<b>MICROLED PROCESSING</b>	Stephanie Baclet
3.15 - 3.30pm	COFFEE BREAK	
3.30 - 4.00pm	<b>END POINTING</b> How to use automatic End Point Detection techniques to monitor and control plasma processes	Dr Mark Dineen
4.00 - 4.30pm	<b>ATOMIC FORCE MICROSCOPY</b> Recent Developments in Oxford Instruments AFM Solutions	Asylum Research
4.30 - 4.45pm	Final remarks and close	Emiel Thijssen